

	Type	Hits	Search Text	DBs	Time Stamp	Comments	Error Definition	Errors	Ref #
1	BR S	4	("4874401" "4933314" "5603892" "6560839").PN.	USPAT; EPO; JPO	2005/05/13 14:08				S1
2	BR S	196	theriault.in.	USPAT; EPO; JPO	2005/03/23 18:05				S2
3	BR S	4	theriault-martin.in.	USPAT; EPO; JPO	2005/03/23 18:06				S3
4	BR S	8	S1 S3	USPAT; EPO; JPO	2005/03/23 18:06				S4
5	BR S	0	S4 and dessica\$3	USPAT; EPO; JPO	2005/03/23 18:07				S5
6	BR S	4	("4874401" "4933314" "5603892" "6560839").PN.	USPAT; EPO; JPO	2005/03/24 10:23				S6
7	BR S	4	theriault-martin.in.	USPAT; EPO; JPO	2005/03/24 10:23				S7
8	BR S	8	S6 S7	USPAT; EPO; JPO	2005/03/24 10:23				S8
9	BR S	5	S8 and nitrogen	USPAT; EPO; JPO	2005/03/24 10:30				S9
10	BR S	1	S9 and humidity	USPAT; EPO; JPO	2005/03/24 10:23				S10
11	BR S	119	(generat\$3 with nitrogen) and (compressed near2 air) and humidity	USPAT; EPO; JPO	2005/03/24 10:30				S11
12	BR S	30	S11 and (membrane with nitrogen)	USPAT; EPO; JPO	2005/03/24 16:05				S12
13	BR S	119	(generat\$3 with nitrogen) and (compressed near2 air) and humidity	USPAT; EPO; JPO	2005/03/24 14:27				S13
14	BR S	0	jp-9109387-\$.did.	USPAT; EPO; JPO	2005/03/24 16:06				S14

	Type	Hits	Search Text	DBs	Time Stamp	Comments	Error Definition	Errors	Ref #
15	BR S	0	jp-3332687-\$.did.	USPAT; EPO; JPO	2005/03/24 16:08				S15
16	BR S	0	"3332687"	JPO	2005/03/24 16:09				S16
17	BR S	4433	@pd="19970415"	JPO	2005/03/24 16:09				S17
18	BR S	271	S17 and wall	JPO	2005/03/24 16:09				S18
19	BR S	7	S18 and bar	JPO	2005/03/24 16:13				S19
20	BR S	0	gb-2235115-\$.did.	JPO	2005/03/24 16:13				S20
21	BR S	0	gb-02235115-\$.did.	JPO	2005/03/24 16:13				S21
22	BR S	0	uk-2235115-\$.did.	JPO	2005/03/24 16:13				S22
23	BR S	1	gb-2235115-\$.did.	DERWENT	2005/03/24 16:13				S23
24	BR S	1	"6655168".pn.	USPAT; EPO; JPO	2005/05/13 14:11				S24
25	BR S	1	S24 and nitrogen	USPAT; EPO; JPO	2005/05/13 14:11				S25
26	BR S	0	S24 and deiscca\$5	USPAT; EPO; JPO	2005/05/13 14:11				S26
27	BR S	0	S24 and desicca\$5	USPAT; EPO; JPO	2005/05/13 14:12				S27
28	BR S	8140	desiccator	USPAT; EPO; JPO	2005/05/13 14:12				S28
29	BR S	92	(desiccator with membrane)	USPAT; EPO; JPO	2005/05/13 14:12				S29

	Document ID	Issue Date	Title	Current OR	Current XRef	Inventor
1	US 5740845 A	1998 0421	Sealable, transportable container having a breather assembly	141/292	141/98; 206/710; 414/217; 414/217.1; 414/411; 414/940	Bonora; Anthony C. et al.
2	US 5735961 A	1998 0407	Semiconductor fabricating apparatus, method for controlling oxygen concentration within load-lock chamber and method for generating native oxide	118/724	118/715; 118/719; 414/937; 414/939; 432/241	Shimada; Masakazu
3	US 5611452 A	1997 0318	Sealable transportable container having improved liner	220/378	141/368; 141/98; 206/454; 206/710; 220/614; 220/681; 220/806; 414/217; 414/217.1; 414/935; 414/940	Bonora; Anthony C. et al.
4	US 5575081 A	1996 1119	Device for transporting magazines for molding wafer-shaped objects	34/218	34/222; 34/224; 414/217; 414/217.1; 414/940	Ludwig; Joachim
5	US 5536320 A	1996 0716	Processing apparatus	118/719	118/715; 414/217; 414/938; 414/939; 414/940	Ushikawa; Harunori et al.

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6	US 5482161 A	1996 0109	Mechanical interface wafer container	206/711	141/98; 206/454; 220/323; 414/217; 414/217.1; 414/292; 414/940	Williams; Randall S. e al.
7	US 5469963 A	1995 1128	Sealable transportable container having improved liner	206/709	206/454; 361/212	Bonora; Anthony C. et al.
8	US 5433574 A	1995 0718	Gas purge unit for a portable container	414/217	414/416.0 3; 414/940	Kawano; Hitoshi et al
9	US 5373806 A	1994 1220	Particulate-free epitaxial process	117/106	117/90; 117/94; 134/1; 361/212; 438/905; 438/935	Logar; Roger E.
10	US 5354198 A	1994 1011	Movable cantilevered purge system	432/5	432/11; 432/152; 432/253	Yates; Cleon R.
11	US 5320218 A	1994 0614	Closed container to be used in a clean room	206/213.1	118/500; 141/67; 141/98; 206/454; 211/41.18; 414/935	Yamashita; Teppei et al.
12	US 5277579 A	1994 0111	Wafers transferring method in vertical type heat treatment apparatus and the vertical type heat treatment apparatus provided with a wafers transferring system	432/5	414/217; 414/937; 414/939; 414/940; 432/241; 432/6	Takanabe; Eiichiro

	Document ID	Issue Date	Title	Current OR	Current XRef	Inventor
13	US 5255783 A	1993 1026	Evacuated wafer container	206/711	141/65; 141/98; 206/454; 206/524.8	Goodman; John B. et al.
14	US 5252133 A	1993 1012	Vertically oriented CVD apparatus including gas inlet tube having gas injection holes	118/725	118/715; 118/724; 118/730	Miyazaki; Shinji et al.
15	US 5169272 A	1992 1208	Method and apparatus for transferring articles between two controlled environments	414/217.1	414/422	Bonora; Anthony C. et al.
16	US 5032545 A	1991 0716	Process for preventing a native oxide from forming on the surface of a semiconductor material and integrated circuit capacitors produced thereby	438/762	257/E21.2 26; 257/E21.2 93; 257/E21.3 96; 438/396; 438/775; 438/791; 438/906; 438/974	Doan; Trung T. et al.
17	US 4957781 A	1990 0918	Processing apparatus	427/255.26	118/715; 118/725; 118/728; 219/385; 219/390; 414/217; 427/248.1	Kanegae; Masatomo et al.

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18	US 4863561 A	1989 0905	Method and apparatus for cleaning integrated circuit wafers	134/1.2	134/1; 134/102.1; 156/345.3 6; 156/345.5 2; 204/192.3 2; 204/298.3 3; 257/E21.2 26; 257/E21.2 27; 438/715; 438/727; 438/906	Freeman; Dean W. et al.
19	US 4804086 A	1989 0214	Transport container with an interchangeable inside container	206/710	211/41.18; 220/371; 414/939; 414/940	Grohrock; Peter
20	US 4745088 A	1988 0517	Vapor phase growth on semiconductor wafers	117/98	117/101; 117/102; 117/103; 117/935; 118/724; 118/730; 148/DIG.1 69; 148/DIG.5 7; 427/248.1; 427/593; 438/488; 438/778; 438/935	Inoue; Yosuke et al.

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21	US 4728389 A	1988 0301	Particulate-free epitaxial process	117/97	117/101; 117/103; 117/928; 117/935; 117/94; 134/1; 361/212; 427/585; 427/595; 438/758; 438/935	Logar; Roger E.
22	US 4724874 A	1988 0216	Sealable transportable container having a particle filtering system	141/98	141/383; 141/85; 414/217; 414/217.1; 414/292; 414/414; 414/608; 414/618; 414/733; 414/939; 414/940; 55/385.1	Parikh; Mihir et al.
23	US 4705444 A	1987 1110	Apparatus for automated cassette handling	414/222.06	118/729; 414/217; 414/217.1; 414/609; 414/618; 414/626; 414/730; 414/733; 414/917; 414/939; 414/940; 432/239	Tullis; Barclay J. et al.

	<b>Document ID</b>	<b>Issue Date</b>	<b>Title</b>	<b>Current OR</b>	<b>Current XRef</b>	<b>Inventor</b>
<b>24</b>	US 4616683 A	1986 1014	Particle-free dockable interface for integrated circuit processing	414/217.1	141/383; 220/502	Tullis; Barclay J. et al.